

# **Implications of the Electron Cloud on the Design of the LHC Vacuum System**

**O. Gröbner**

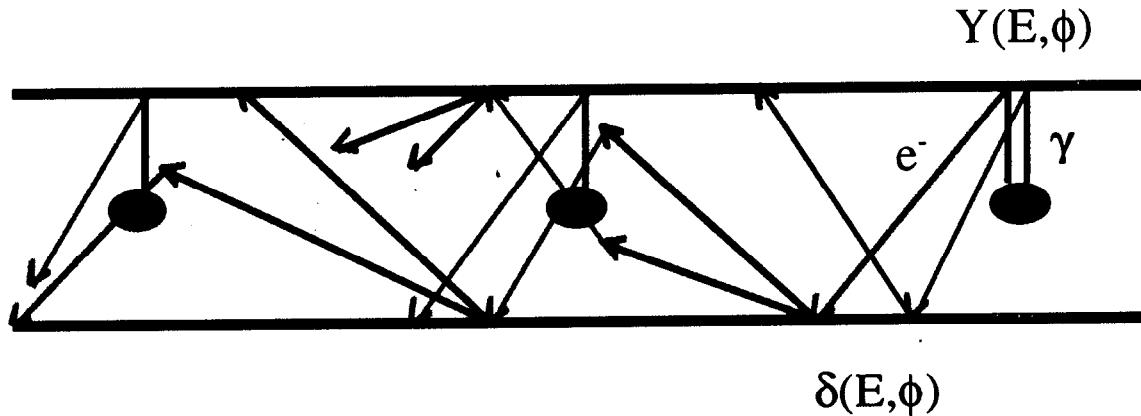
## **Credits :**

**CERN : V. Baglin, O. Brüning, I.R. Collins, J. Gómez-Goñi,  
B. Henrist, N. Hilleret, M. Jimenez, N. Kos, J-M. Laurent,  
M. Pivi, F. Ruggiero, F. Zimmermann**

**INFN : R. Cimino**

**INP : V.V. Anashin, R.V. Dostovalov, N.V. Fedorov, A.A.  
Krasnov, O.B. Malyshev, E.E. Pyata**

# Electron cloud generated heat load in the LHC beam screen



## Key parameters

Synchrotron radiation intensity,  $\gamma$

$Y(E, \phi)$  photoelectric yield

$\delta(E, \phi)$  secondary electron yield,  $E_{\max}$ ,  $\delta_{\max}$

Energy distribution of secondary electrons

Photon reflectivity (magnetic field)

Beam screen shape and diameter

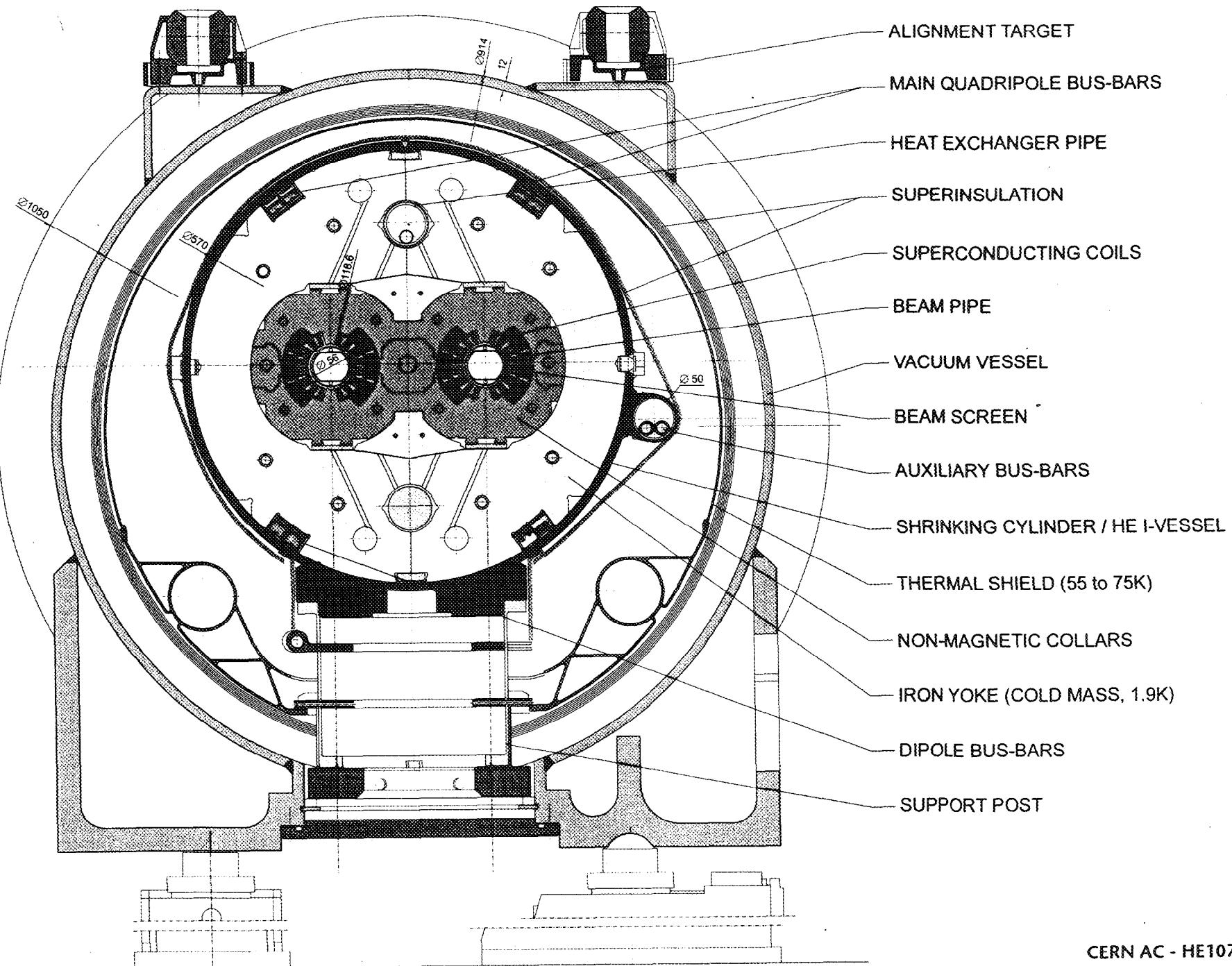
Bunch intensity and spacing

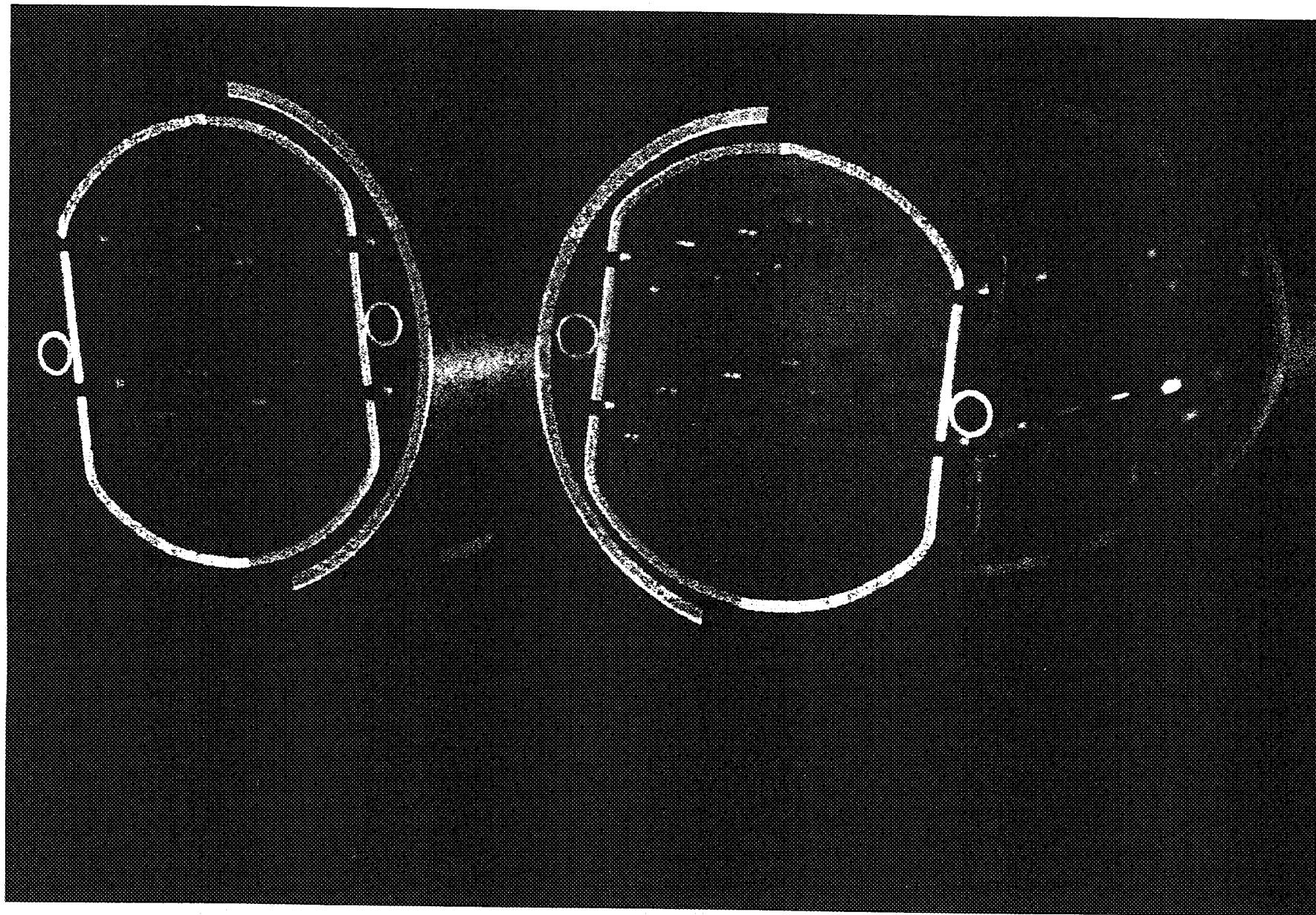
External fields (magnetic, electric, space charge)

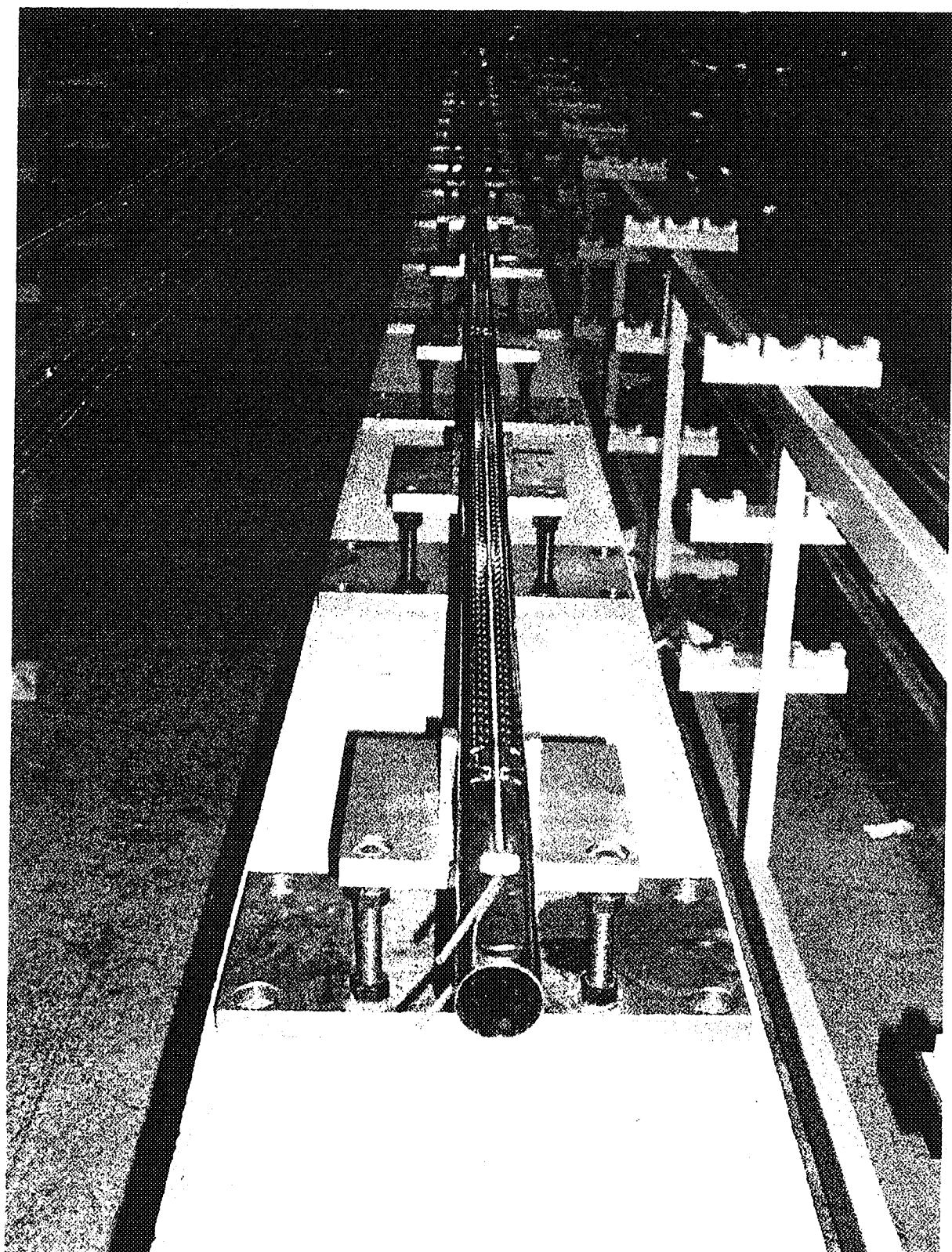
## Gas load

$$Q_{cloud} = k \frac{\eta_e P_{lin}}{\langle E_{cloud} \rangle}$$

# LHC DIPOLE : STANDARD CROSS-SECTION

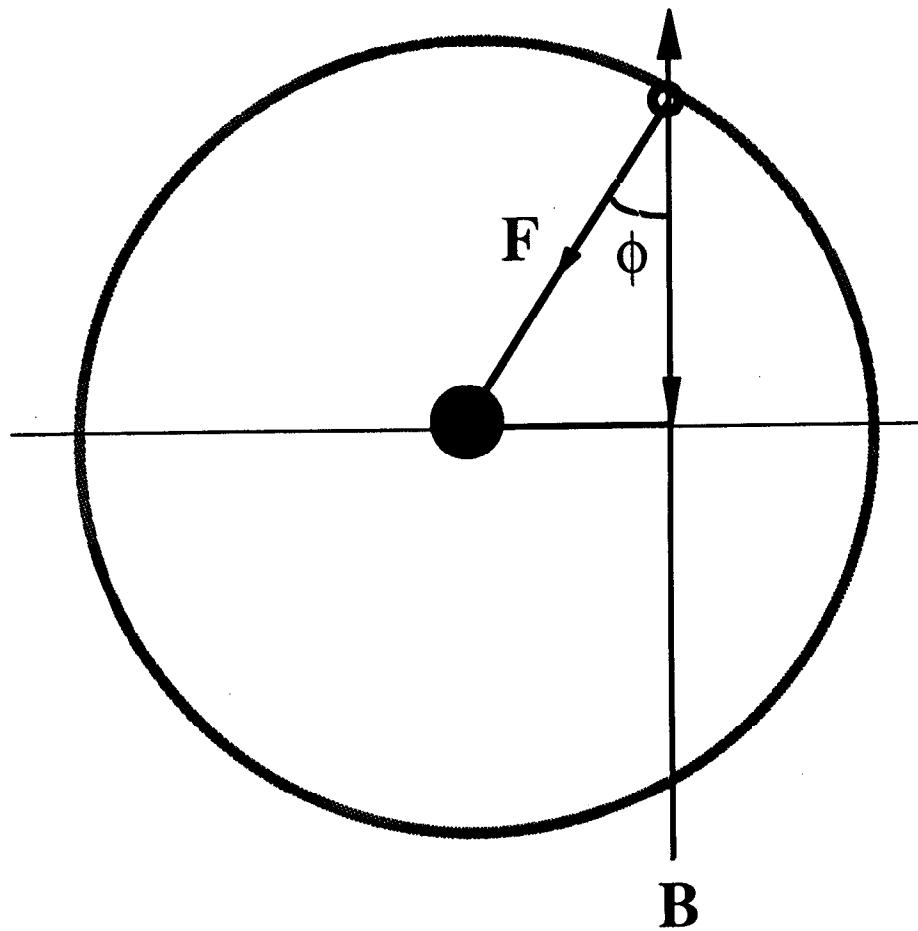






**Dipole beam screen for String2**

## Effect of the magnetic field in a dipole



Averaged over  $2\pi$ , the projection of the kick in the direction of the magnetic field gives an energy transfer to the electrons which is  $1/2$  of the value in a field free region

The energy transfer perpendicular to the magnetic field is negligible -> the electron makes about 60 cyclotron periods during a bunch passage

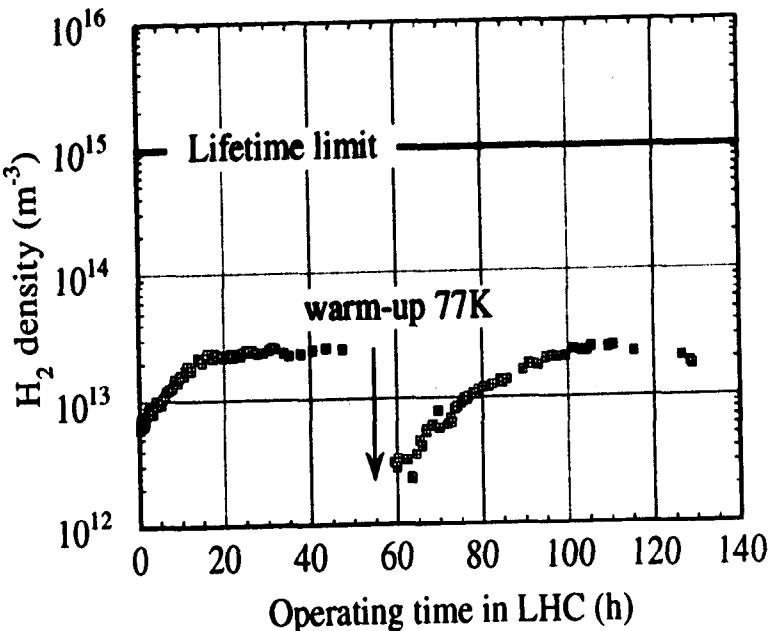
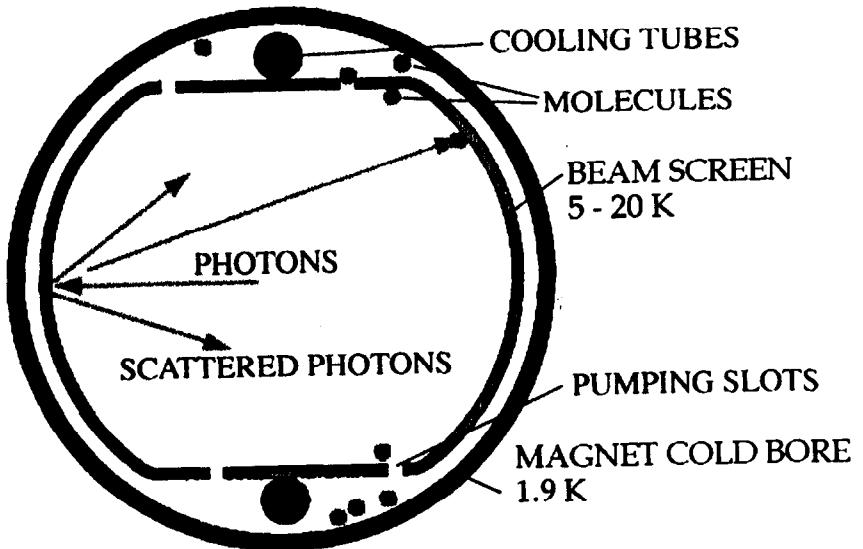
# LHC vacuum with synchrotron radiation.

Synchrotron radiation photons desorb strongly bound gas molecules which are cryosorbed and gradually accumulate on the cold beam screen.

Scattered/reflected photons re-desorb these molecules at a rate increasing with coverage, leading in turn to an increasing gas density (pressure).

The increase in pressure due to 'recycling' of molecules increases the probability for gas to escape through the pumping slots and to be permanently cryosorbed on the 1.9K cold bore. This effect stabilises the gas density in the beam pipe to a safe value.

Without pumping holes, the beam screen would have to be warmed-up periodically to pump-out condensed gas.



Test run at INP in Novosibirsk, scaled to LHC parameters and for initial operation at ~1/10 of the nominal beam current illustrating the effect of recycling of gas and warming-up of the beam screen.

## Some basic equations

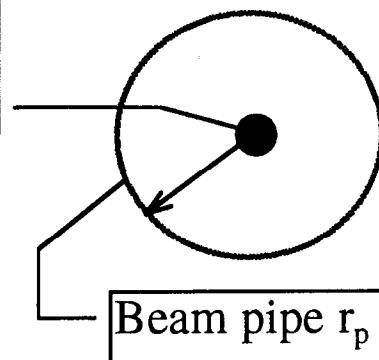
$$E(r) = \frac{\lambda}{2\pi\epsilon_0 r} \quad \text{with}$$

the momentum transfer

$$\Delta p = e E \tau = \frac{e^2 N_b}{2\pi\epsilon_0 c r}$$

hence independent of the bunch length

$$\lambda = \frac{e N_b}{c \tau}$$



The velocity due to this momentum transfer is

$$\Delta v = \frac{\Delta p}{m} = \frac{e^2 N_b}{2\pi\epsilon_0 m c r} = 2c r_e \frac{N_b}{r}$$

introducing the classical electron radius

$$r_e = \frac{e^2}{4\pi\epsilon_0 m c^2} = 2.8 \cdot 10^{-15} \text{ m}$$

The transit time condition requires

$$\frac{2r_p}{v} = t_{bb}$$

and introducing the distance between successive bunches

$$L_{bb} = c t_{bb}$$

gives a very simple relation

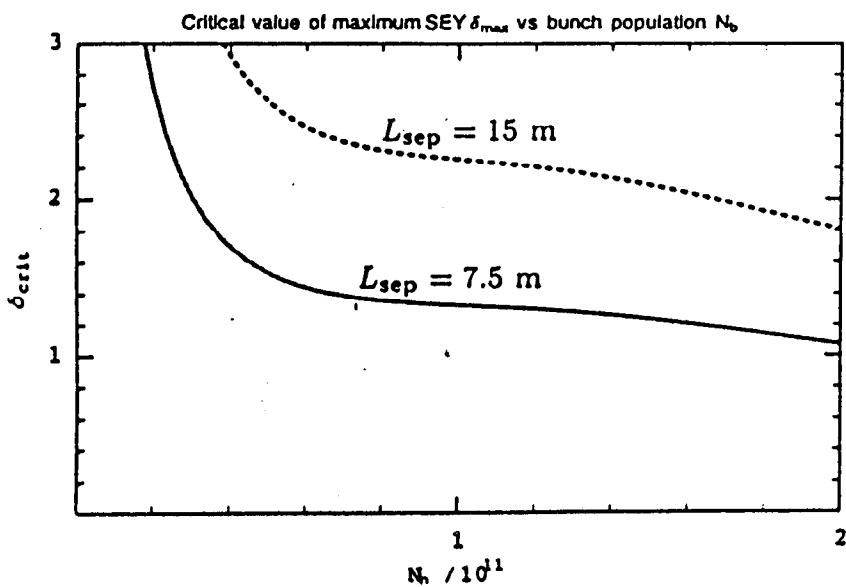
$$N_b = \frac{r_p^2}{r_e L_{bb}} \quad (\sim \frac{1}{3} \text{ of } L_{bb})$$

The energy resulting from the kick of a bunch is

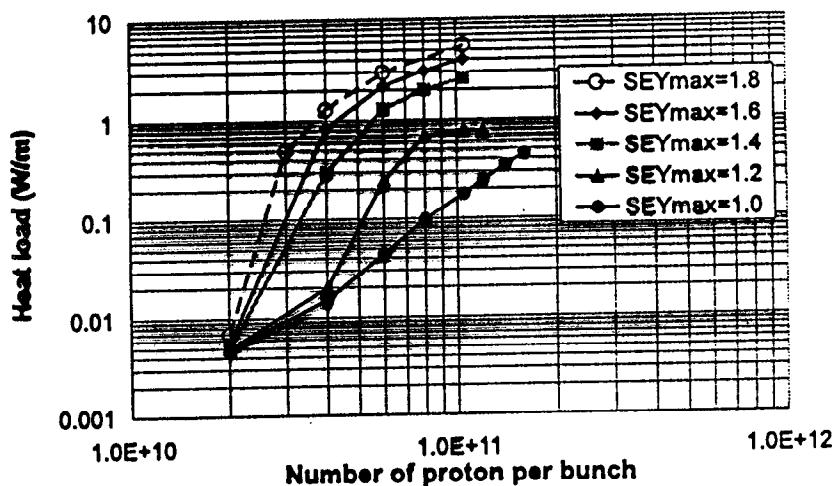
$$\Delta W = \frac{\Delta p^2}{2m}$$

or

$$\Delta W = 2 \frac{mc^2}{e} r_e^2 \left( \frac{N_b}{r} \right)^2 \text{ (eV)}$$



LHC-PR 166



PAC-99

$$\left. \begin{array}{l} \delta_{ye} = 0.2 \\ R = 0.1 \end{array} \right\} \quad \left. \begin{array}{l} \text{assumed for baseline} \\ 0.05 \text{ in, ribbed} \\ 0.05 \end{array} \right\}$$

Hence heat load should be reduced by a factor 8

# INT experiment

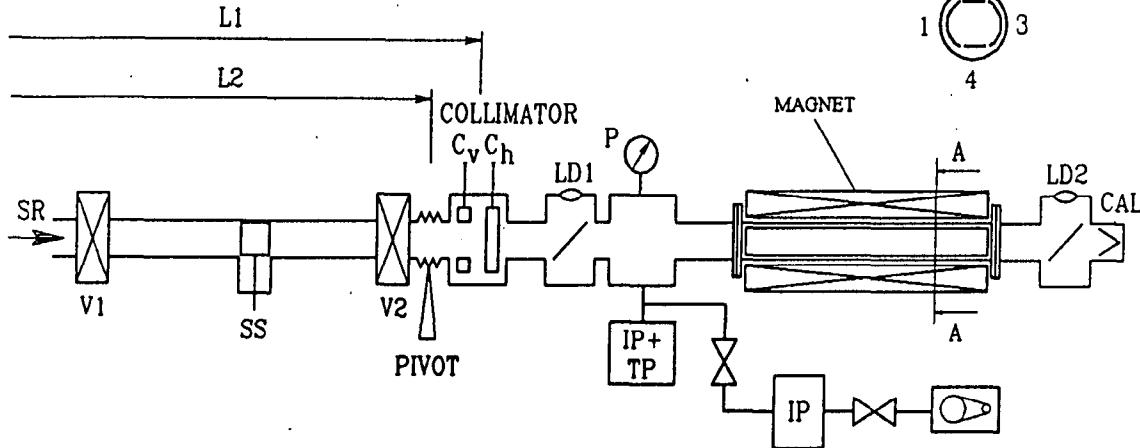


Figure 2: Set-up for measurements of the photon reflectivity and azimuthal photoelectron distribution in a magnetic field.

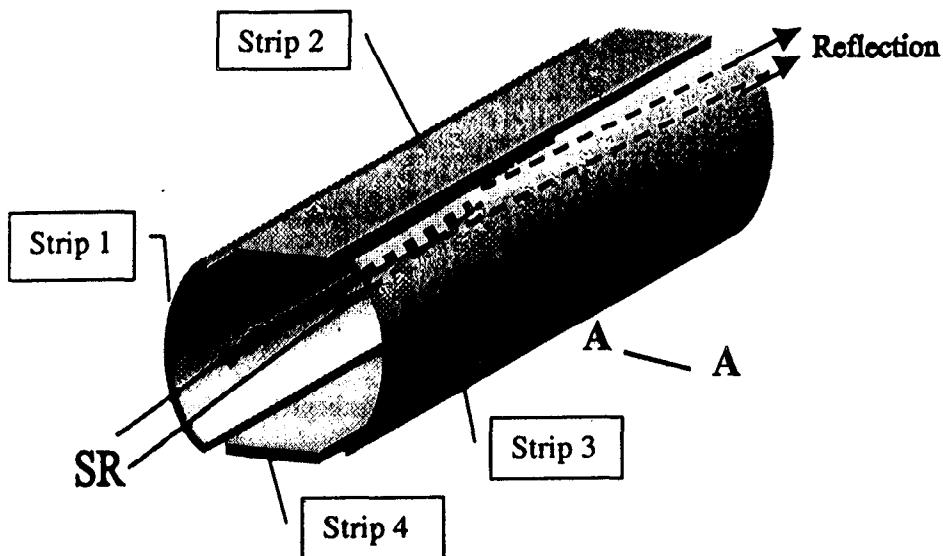
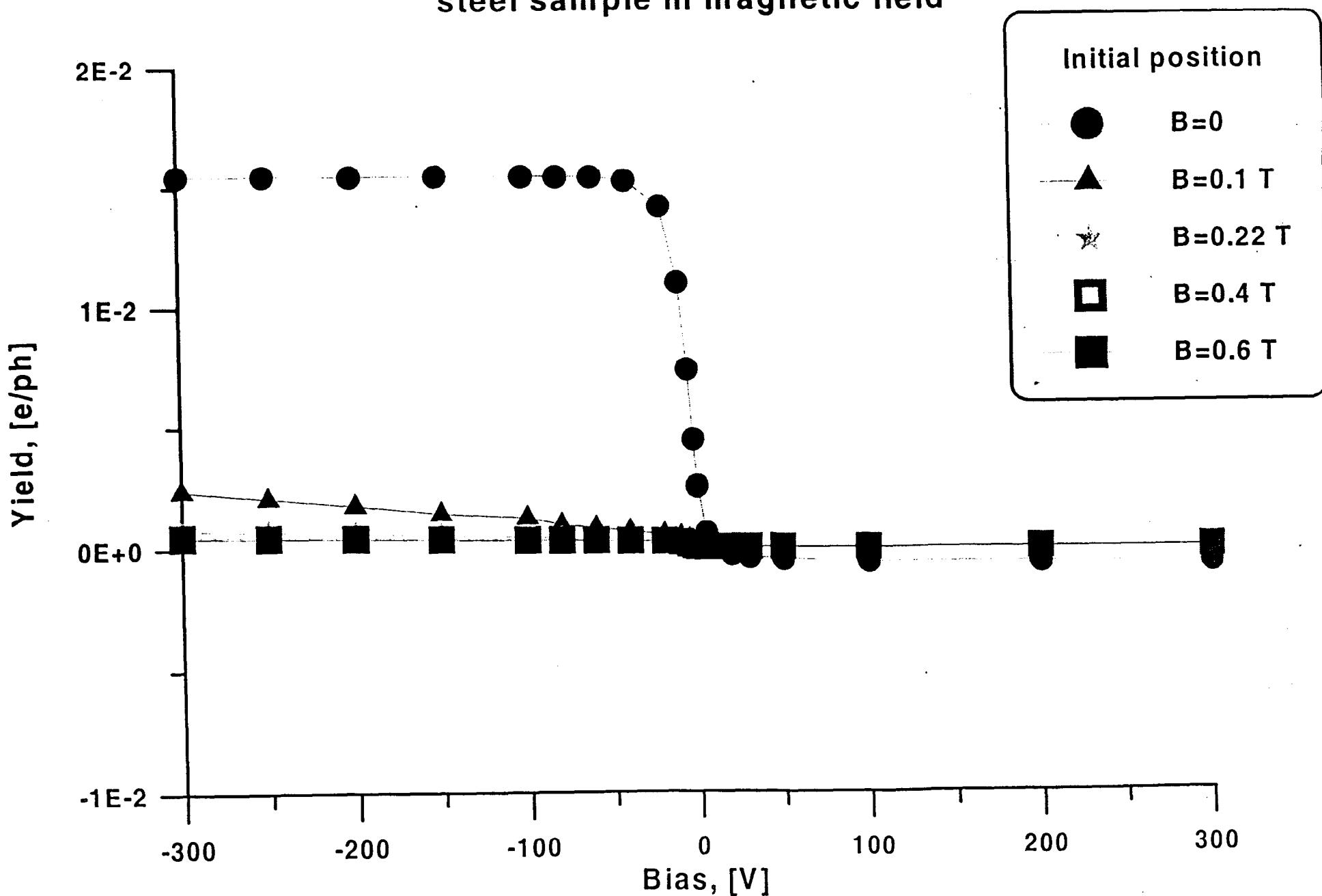


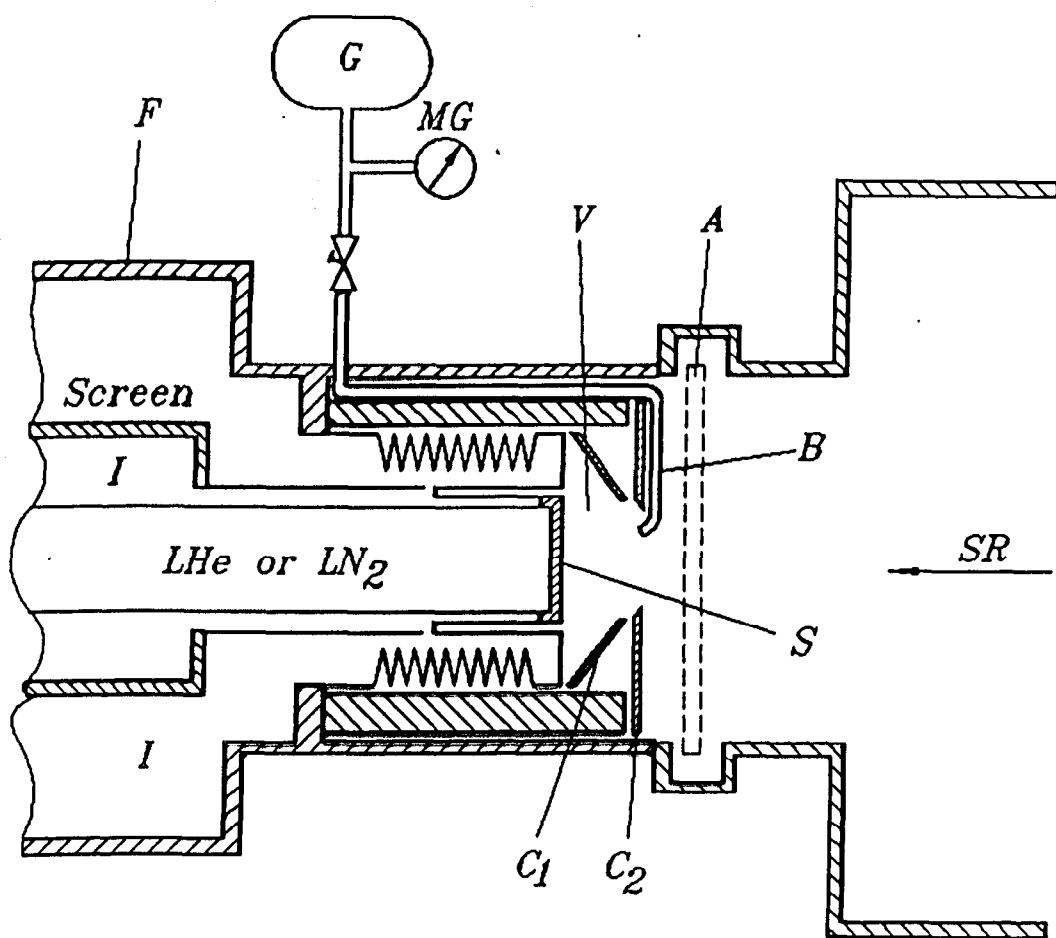
Figure 3: ample configuration for experiments of the photon reflectivity and azimuthal photoelectron distribution in a magnetic field.

Sample	Critical Energy $E_c$ (eV)	Forward Scattered Reflection		Diffuse Reflectivity $R_{dif}$	Photon Adsorption $R_I$	$\frac{R_{dif}}{R_I + R_{dif}}$	Y (electron/photon)
		$R_e$ (by current)	$R_w$ (by power)				
Smooth surface	20	0.67	—	0.04	0.29	0.13	0.03
Saw-tooth surface	49	0.035	—	0.22	0.74	0.23	0.049
	246	0.026	0.03	0.185	0.79	0.19	0.063

EVC-6 Lyon Dec 1999

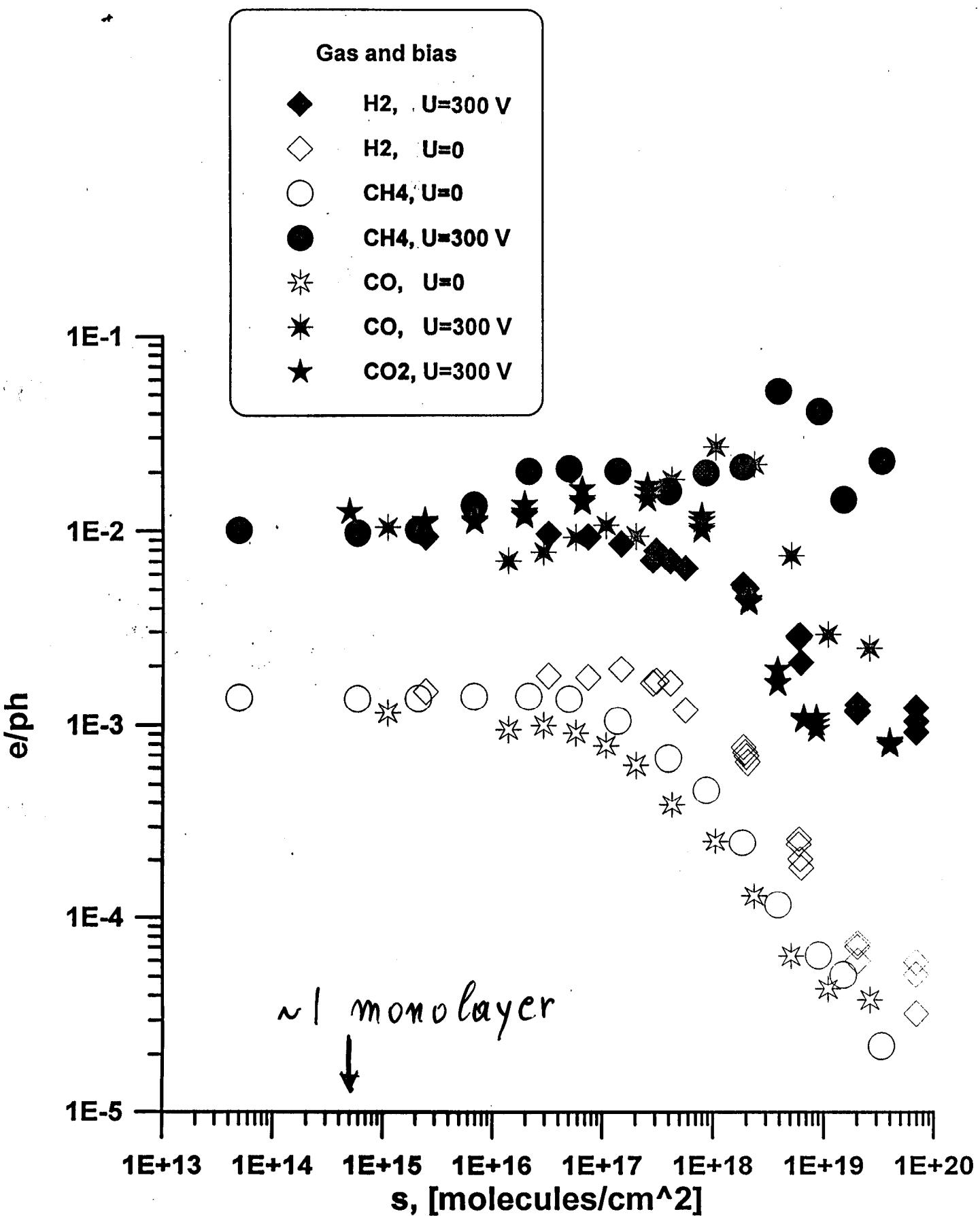
Expt. 2.2. Photoelectron emission  
from copper laminated stainless  
steel sample in magnetic field

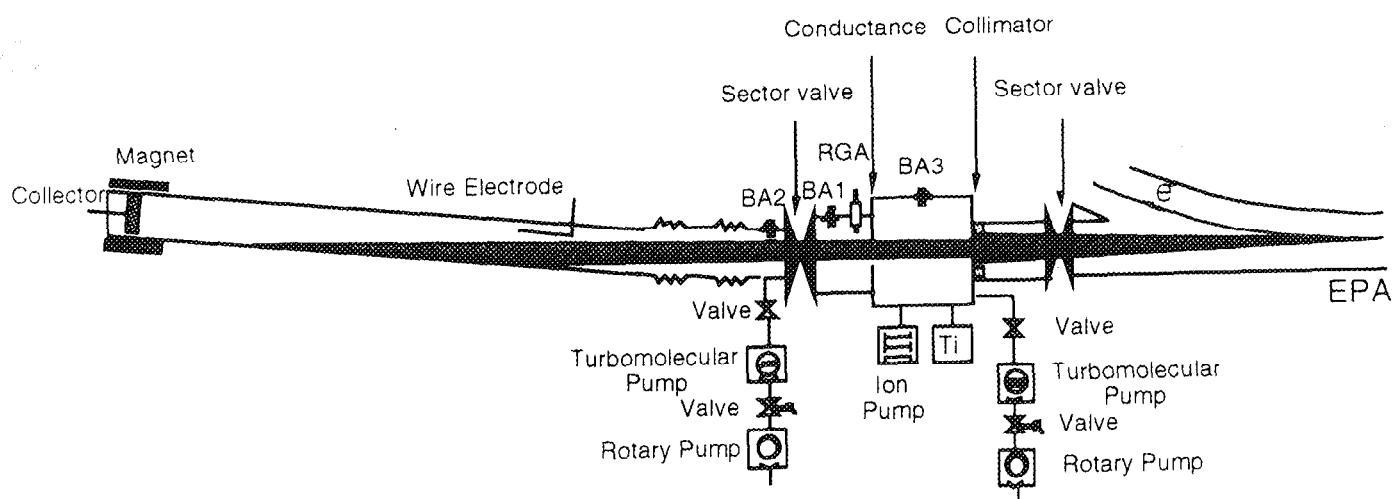
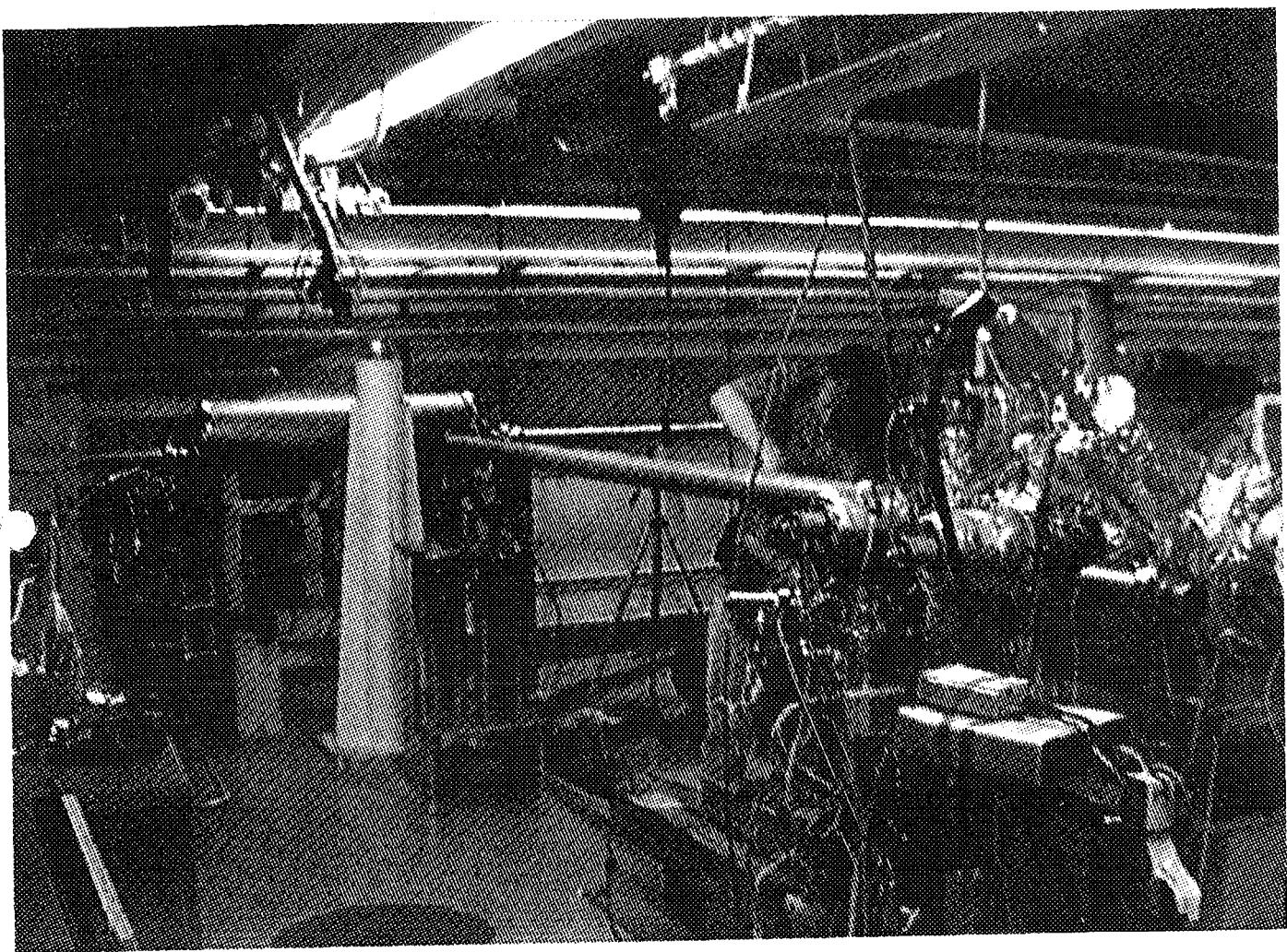




**Figure 1.** The experimental set-up on the synchrotron radiation beam line.  $F$  is the cryostat,  $I$  is the isolating vacuum,  $V$  is the experimental volume which can be separated from the beam line with the valve  $A$  shown in the closed position. The membrane gauge  $MG$  measures the gas pressure in the volume  $G$  which is injected via the pipe  $B$  and condensed onto the substrate  $S$  at cryogenic temperature.  $C_1$  and  $C_2$  are the insulated collector electrodes.

# Photoemission from condensed gases on the stainless steel substrate





# EPA photoelectrons Compilation

au 28/11/97

$$Y [e.photon^{-1}] = \frac{I/q}{\Gamma F_{\text{Collimator}} (1 - R)} \frac{L_{\text{Hit}}}{L_{\text{Collected}}}$$

Date	Tube	status	308 MeV		500 MeV	
			R (%)	Y(e/ph)	R (%)	Y(e/Ph)
27/97	Cu roll bonded	Unbaked	80.9	0.114	77	0.318
28/8/97	Cu electroplated	Unbaked	5	0.084	6.9	0.078
17/9/97	Cu roll bonded air baked	Unbaked	21.7	0.096	18.2	0.180
13/11/97	Cu ribbed	Unbaked	1.8	0.053	-	-
14/11/97		150, 9 hours	1.3	0.053	1.2	0.052
17/11/97		150, 24 hours	1.3	0.040	1.2	0.040
18/11/97	Ti Zr	Unbaked	20.3	0.055	17.1	0.078
19/11/97		120, 12 hours	19.5	0.048	16.7	0.072
20/11/97		250, 9 hours	19.9	0.026	17.4	0.040
25/11/97		350, 10 hours	20.6	0.015	16.9	0.028
28/11/97		350, 10 h after saturation with 5E15 CO/cm <sup>2</sup>	20.7	0.016	-	-

I photoyield current [A]

$$q = 1.602 \times 10^{-19} C$$

$$\Gamma [\text{photons.s}^{-1}] = 1.0029 \times 10^{15} I_{\text{Beam}} [\text{mA}] E_{\text{Beam}} [\text{GeV}]$$

F<sub>Collimator</sub> = 46 % at 308 MeV

= 65 % at 500 MeV

$$L_{\text{Hit}} = 3.414 \text{ m}$$

$$L_{\text{Collected}} = 0.500 \text{ m (computed)}$$

R = reflection

# RIBBED COPPER SURFACE FOR LHC BEAM SCREEN

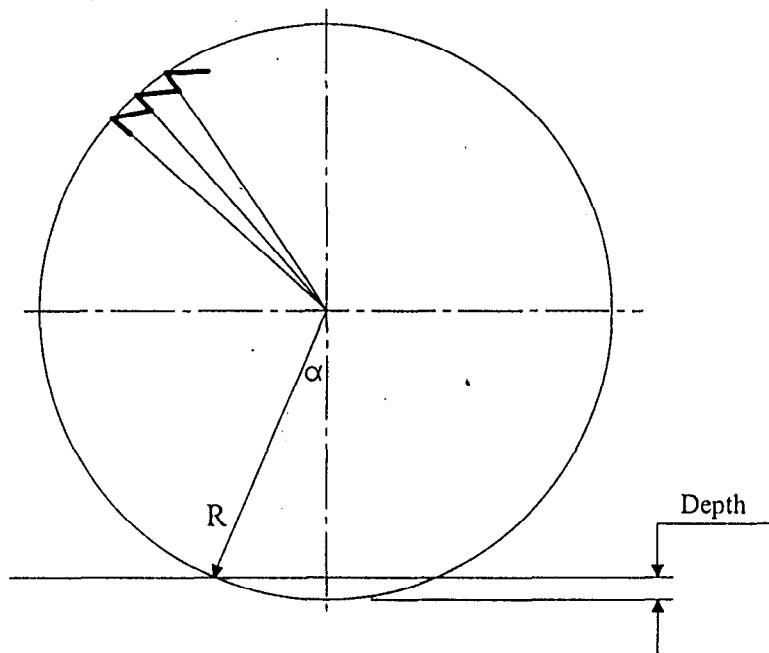


Figure 1

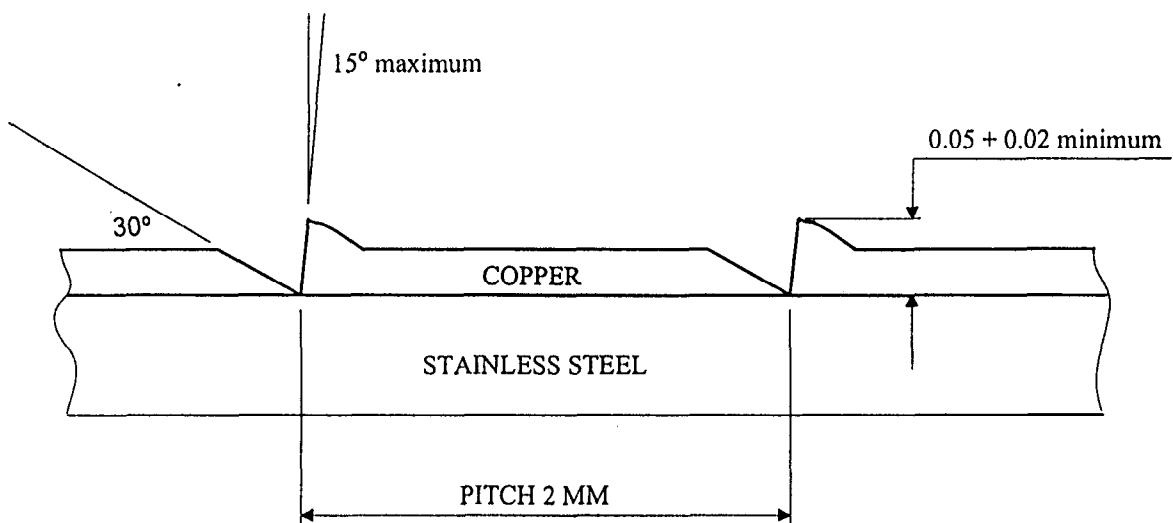


Figure 2

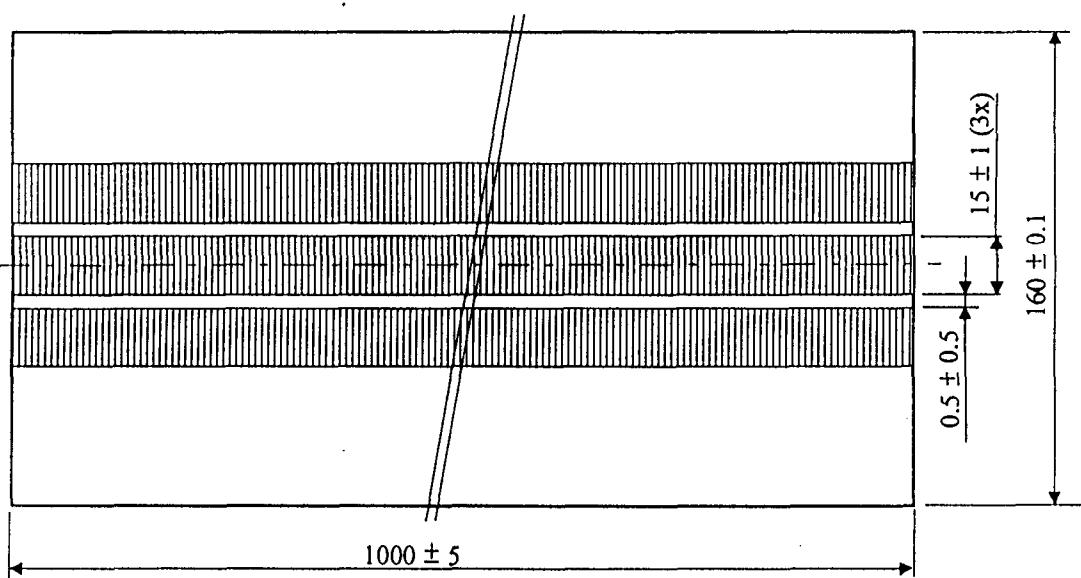
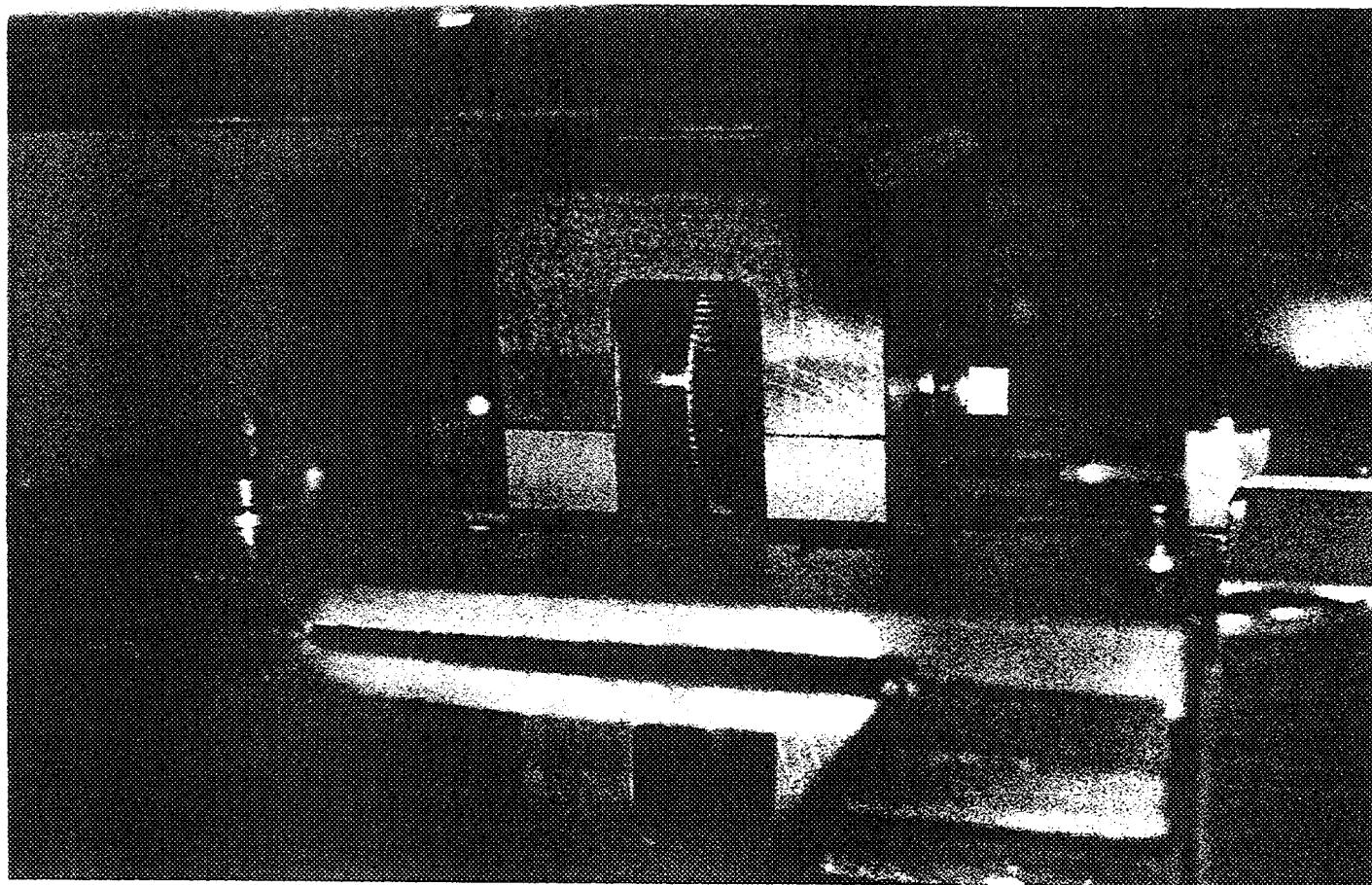


Figure 3

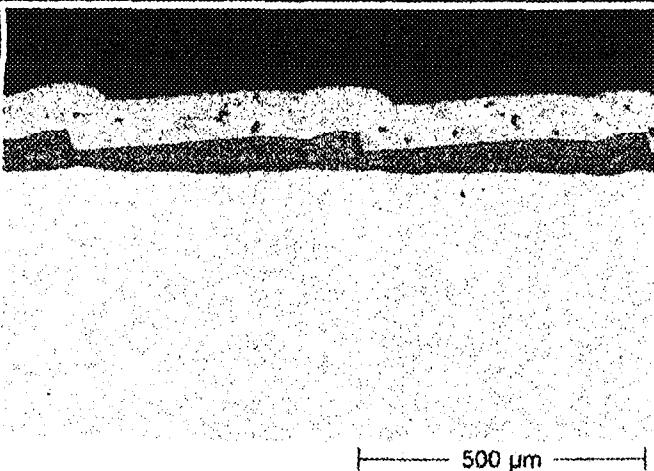
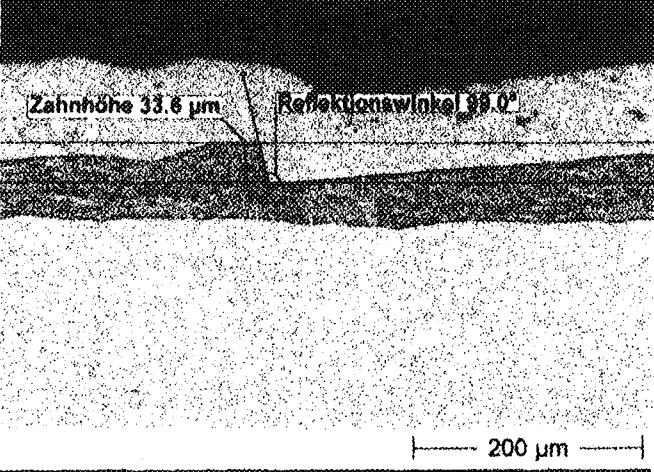
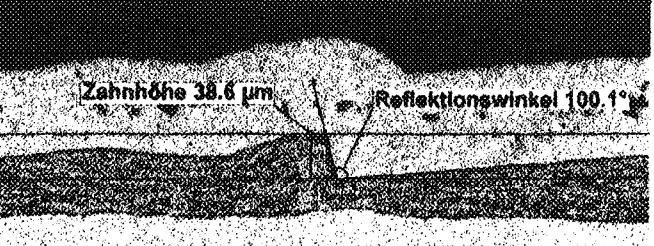
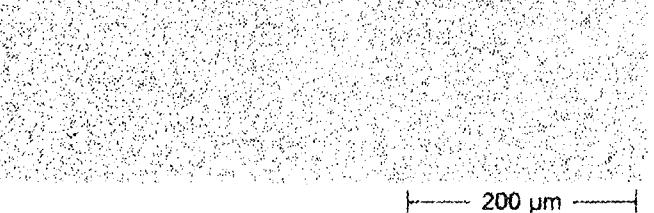
Ian Collins LHC/VAC

LHC MAC #8

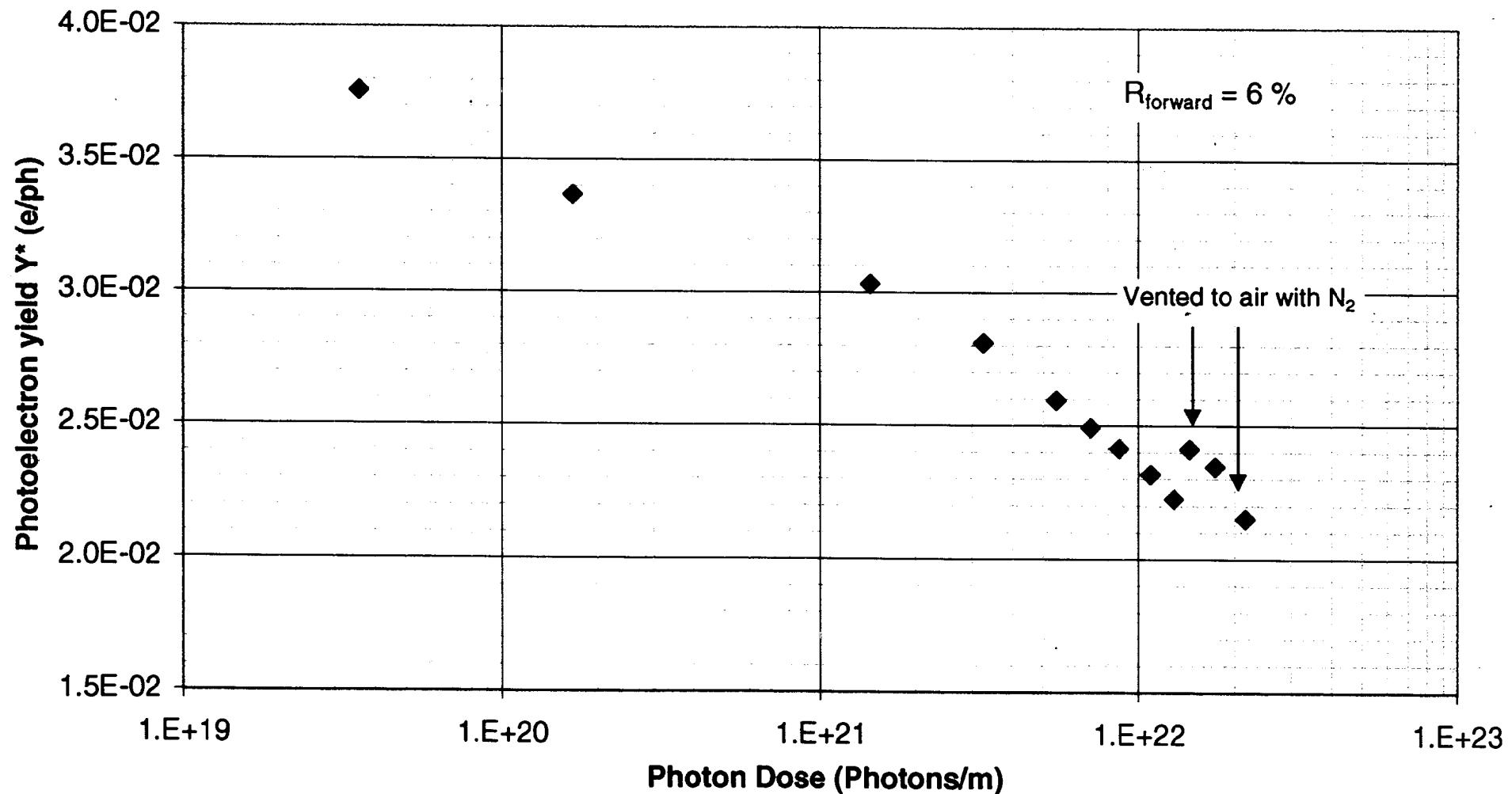
Heraeus



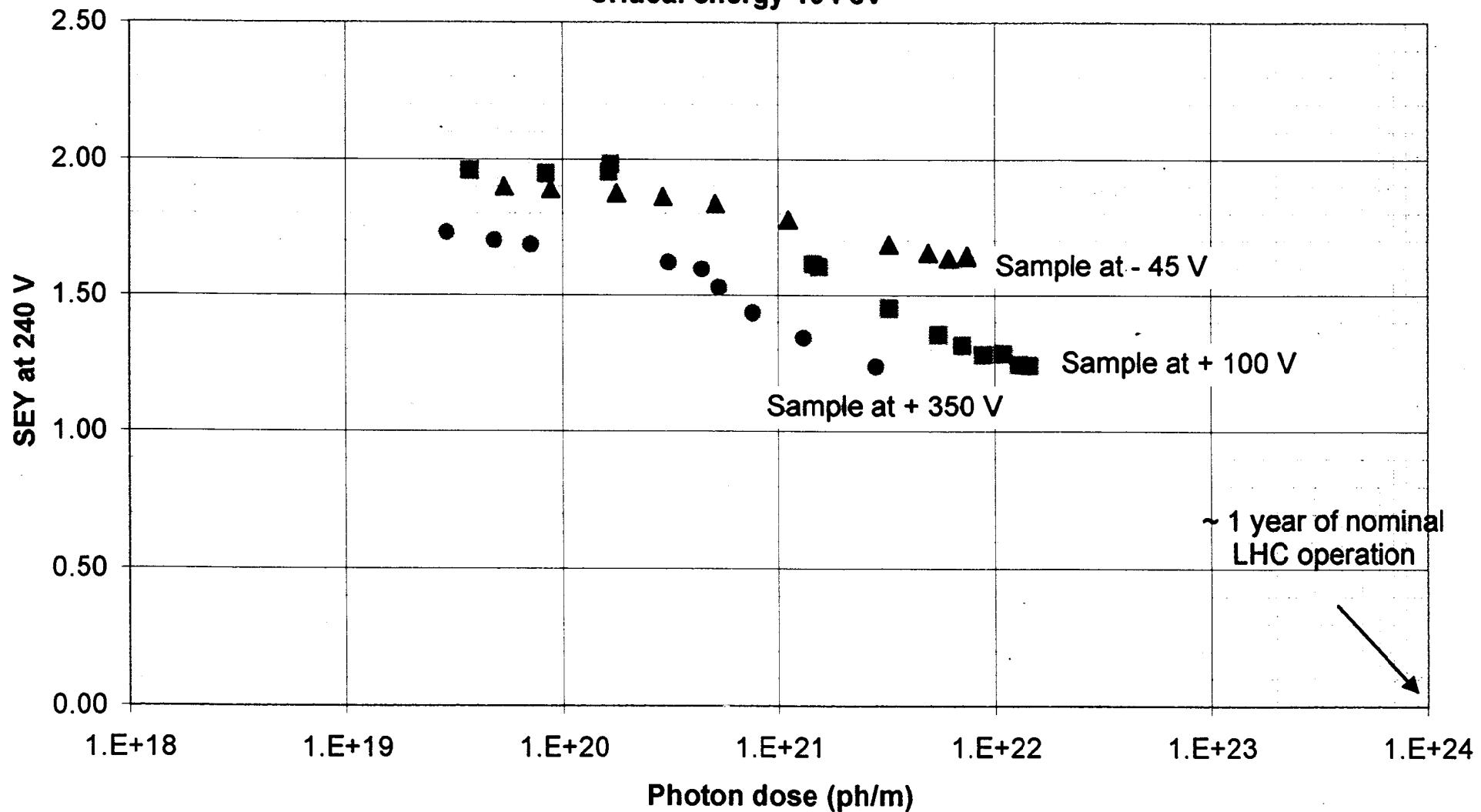
W. C. Heraeus GmbH & Co. KG

<b>Heraeus</b> WCH-GBM-TCS Hellenkamp Tel. 06181/35-493 Fax. 06181/35-5318	Material: Stahl - Cu Band Allgemeines: CERN - Profilierungsversuch Atzmittel: Au-Atzmittel	<b>Metallographie</b> P00361 22.06.1999 135 80 008 H.Eisentraut
		906P0467 Probe vom 17.06.99 - Links 100 1
		906P0468 Probe vom 17.06.99 - Links
		200 1 906P0471 Probe vom 17.06.99 - Links
		200 1

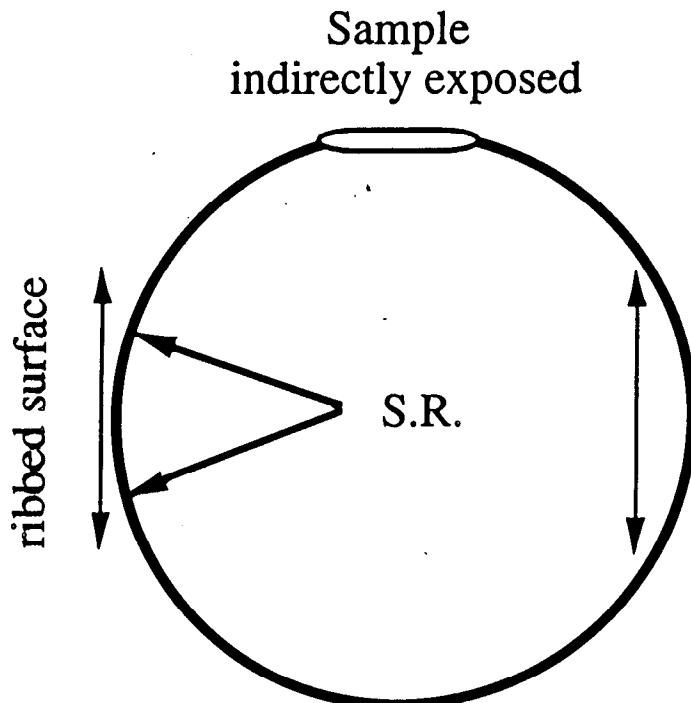
Photoelectron Yield per absorbed photon for a sawtooth chamber  
EPA critical energy 194 eV, Wire polarised at + 1kV



**SEY vs photon dose at EPA**  
**Critical energy 194 eV**



## Beam scrubbing time for the LHC arc scaled from EPA test



S.R. hits the copper test chamber along a ribbed surface

SEY as a function of the photon dose (indirectly exposed sample with bias)

Scrubbing effect scales with the specific surface area :  
factor ~ 2 less for the beam screen.

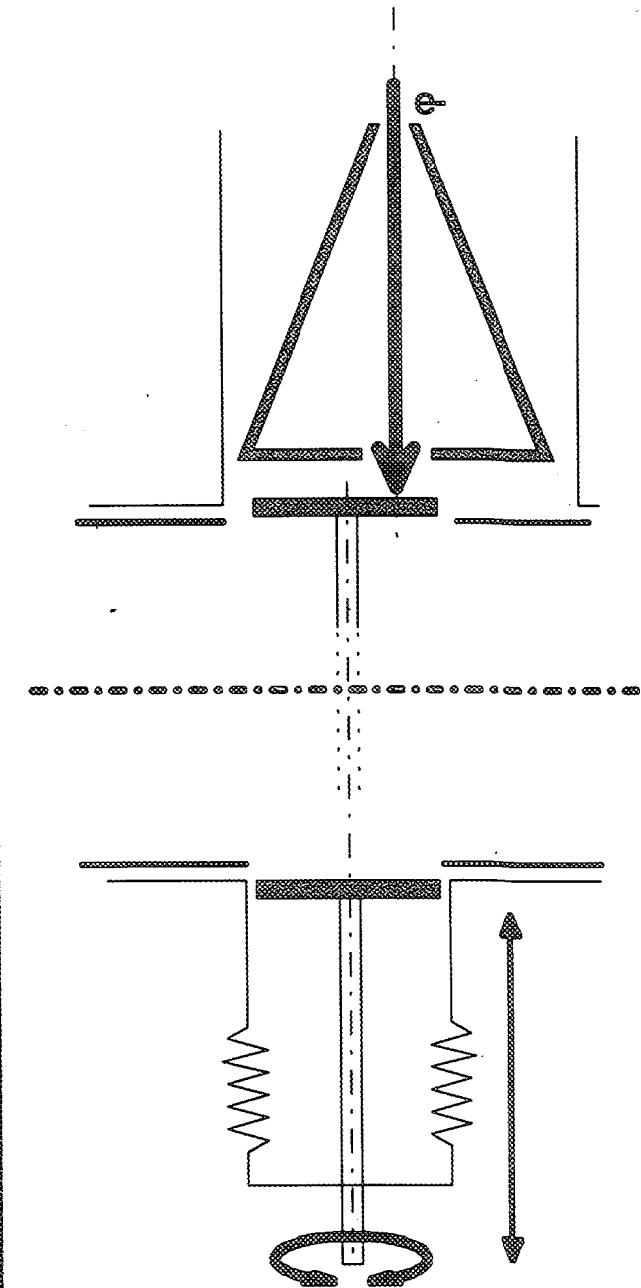
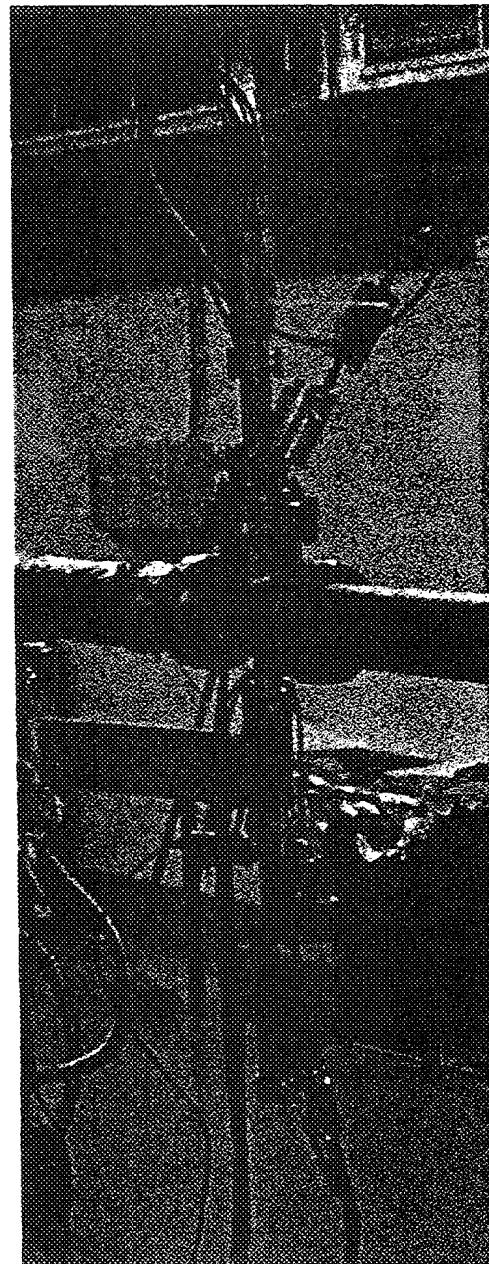
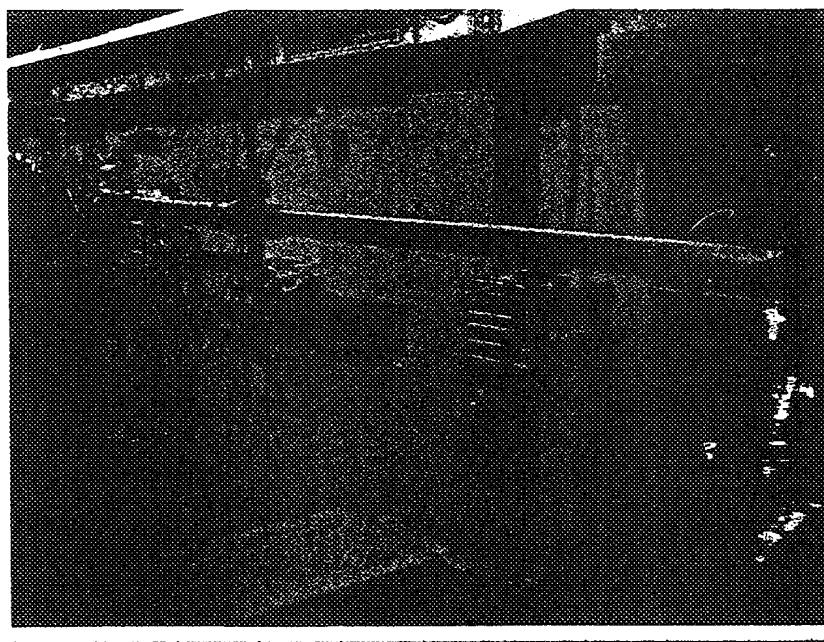
The sample bias simulates the average electron energy for the cloud. However, the biased sample may collect more photo-electrons than a grounded surface.

At 350 V bias the clean-up is ~5 times faster as compared to 100 V.

$10^{22}$  photons/m in EPA equivalent to ~ 7 Ah in LHC.

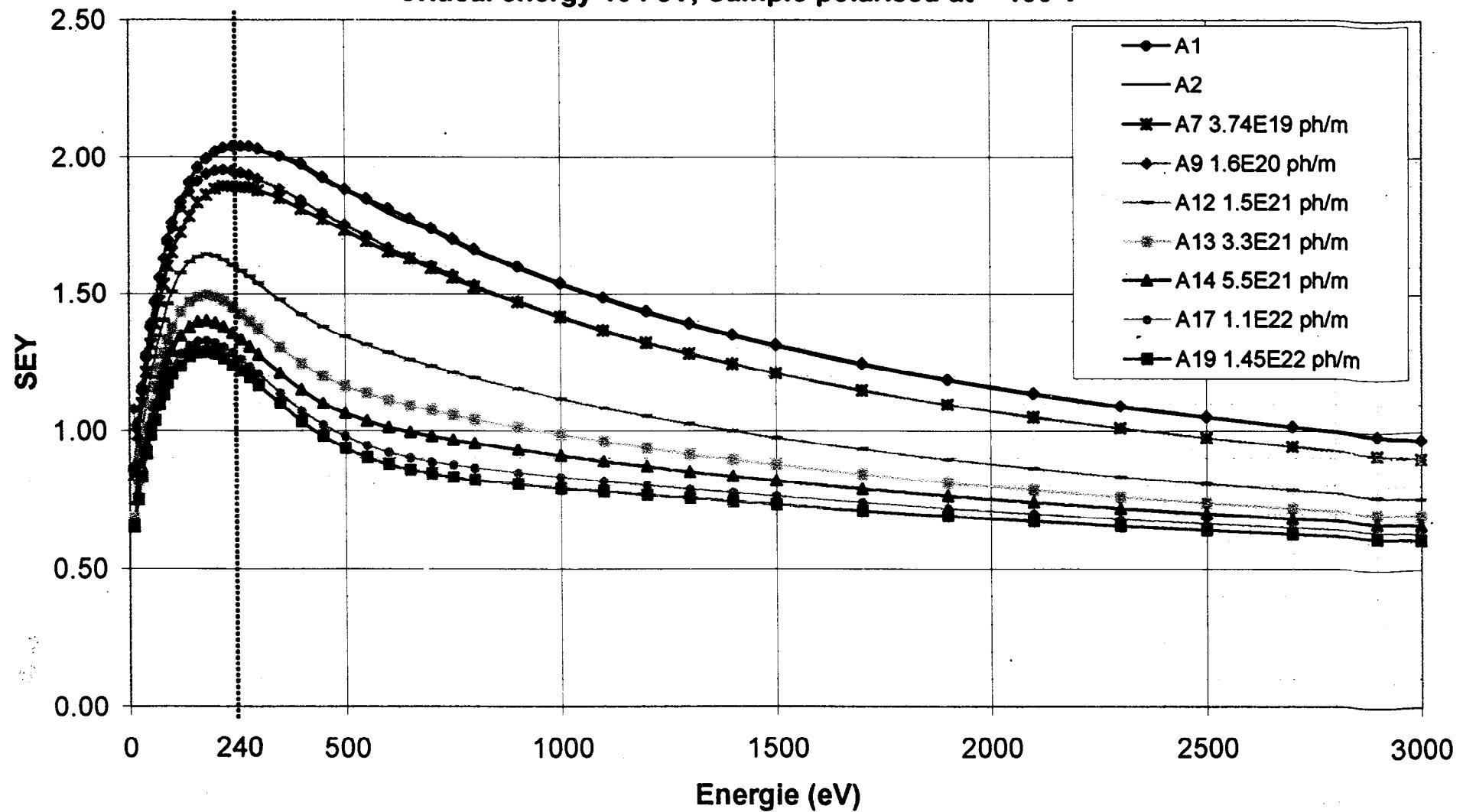
Installation in EPA (11<sup>th</sup> of october 1999)

Movable sample holder (remotely controlled by labview)



LHC VAC SL

SEY vs photon dose at EPA  
Critical energy 194 eV, Sample polarised at + 100 V



Estimated nominal and ultimate heat loads due  
to electron cloud on the dipole beam screen

(Simulations by F. Zimmermann)

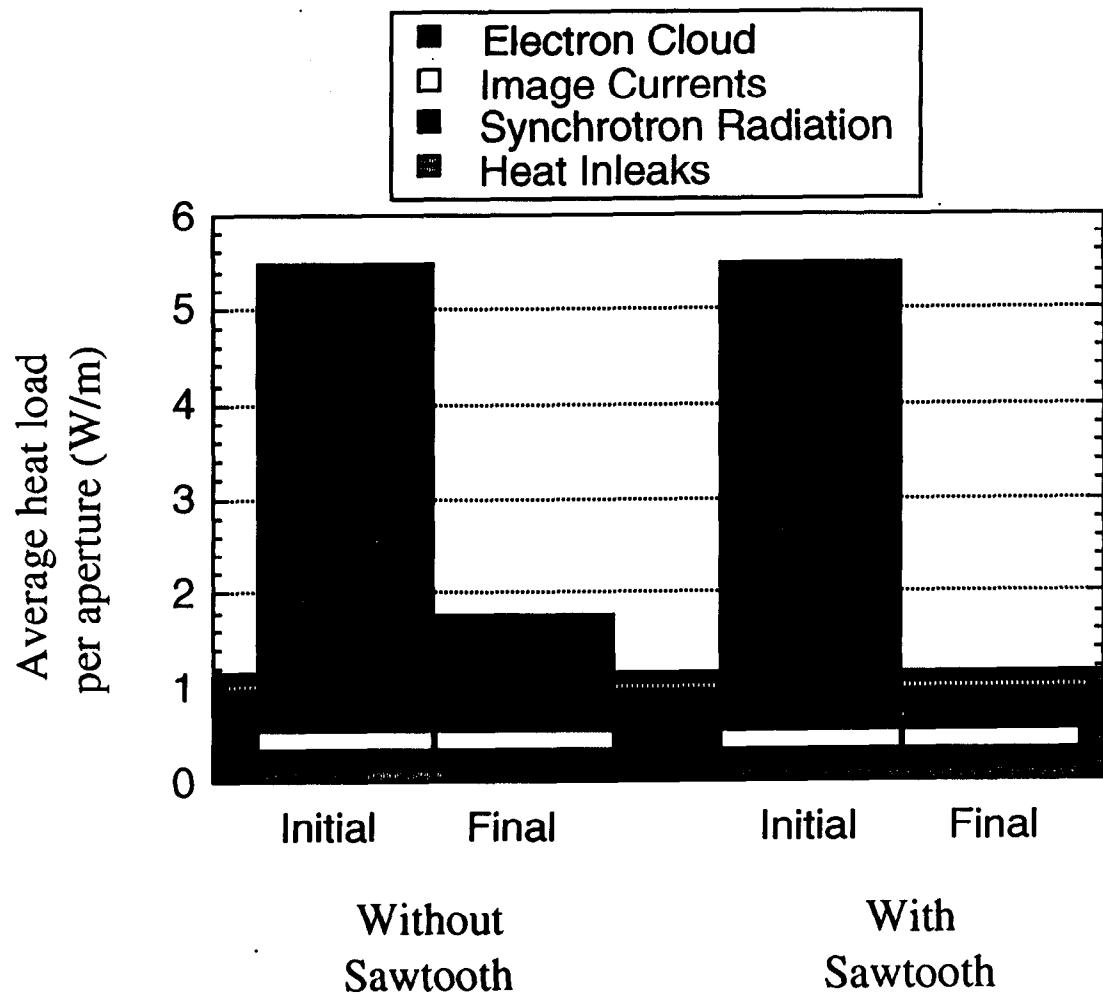
Parameter	Without Saw-tooth		With Sawtooth	
	Initial	Final	Initial	Final
Reflectivity, R	1.0	1.0	0.1	0.1
Photoelectron yield, Y	0.2	0.1	0.05	0.025
Secondary electron yield maximum, $\delta_m$	2.3	1.1	2.3	1.1
$E_{max}$ (eV)	300	450	300	450
Nominal Heat load, P (W/m)	5.0	1.5	5.0	0.045
Ultimate Heat load, P (W/m)	7.6	3.4	7.6	0.120

$$P_{final} = R \cdot P_o(\delta_m) \cdot Y$$

for  $\delta < \delta_{crit}$

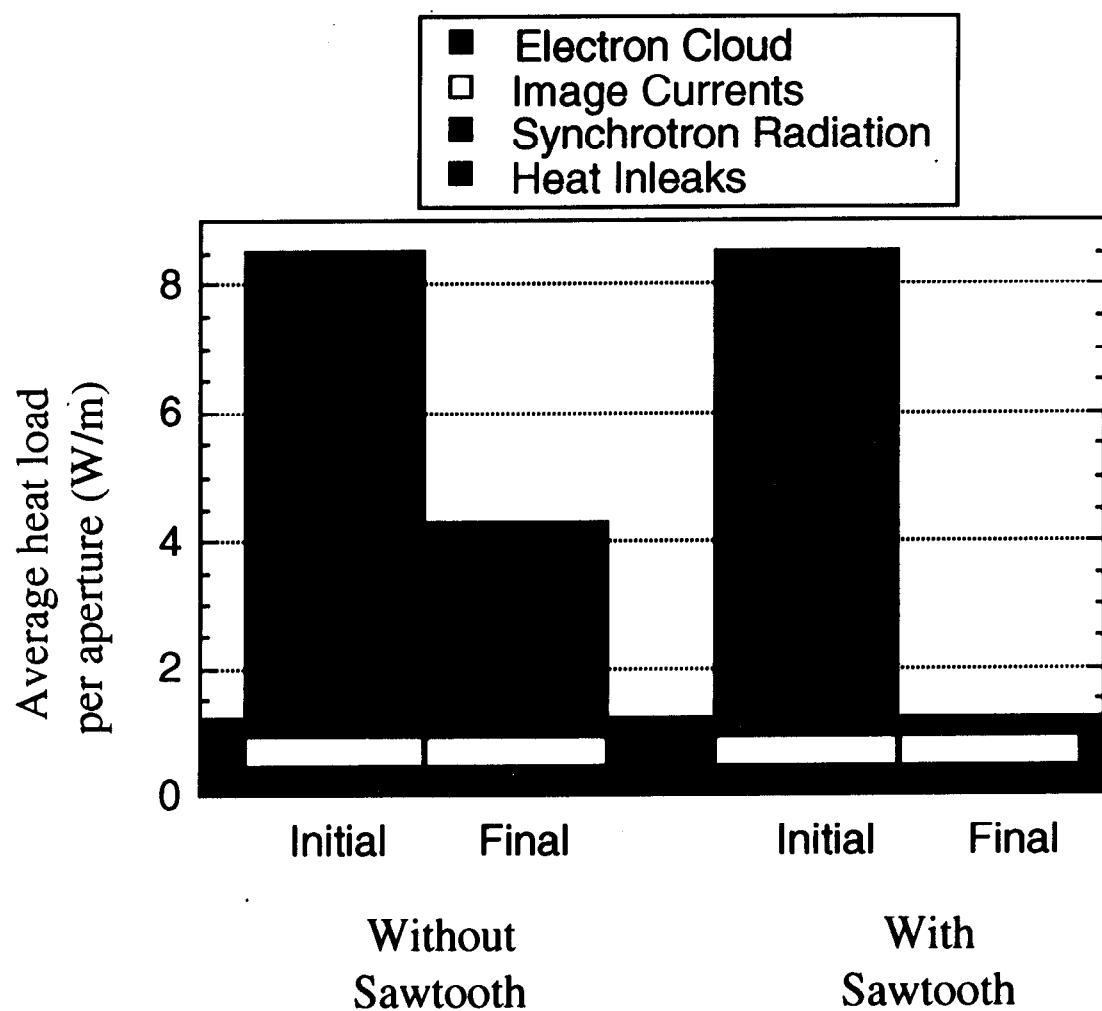
**Estimated heat loads per aperture at 4.6-20K  
for nominal operation (0.56A)**

Installed cooling capacity = 1.17 W/m

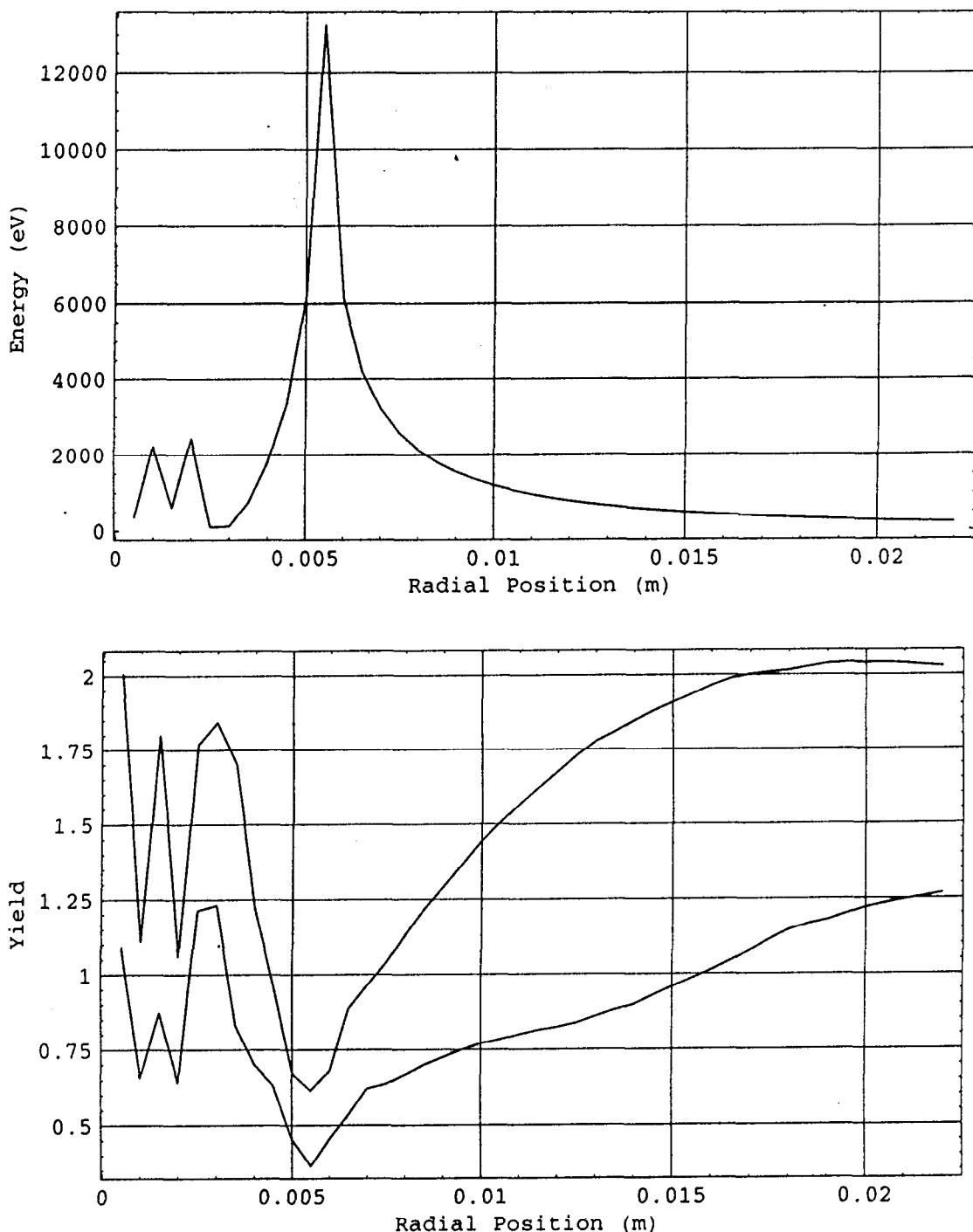


Estimated heat loads per aperture at 4.6-20K  
for ultimate operation (0.85A)

Installed cooling capacity = 1.17 W/m



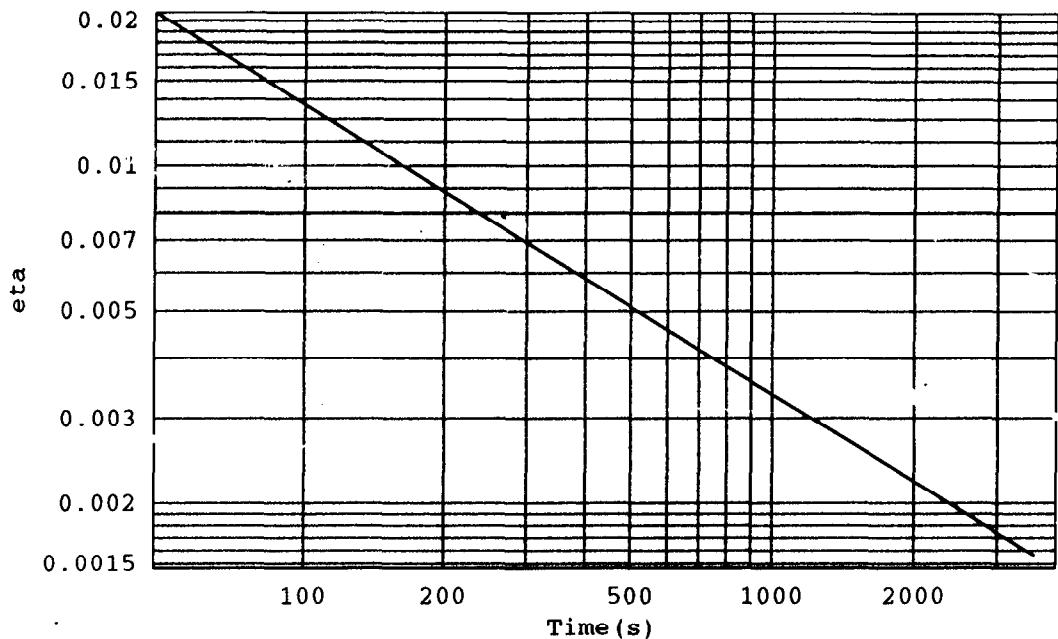
Electron energy and secondary electron yield vrs.  
radial position at nominal LHC conditions



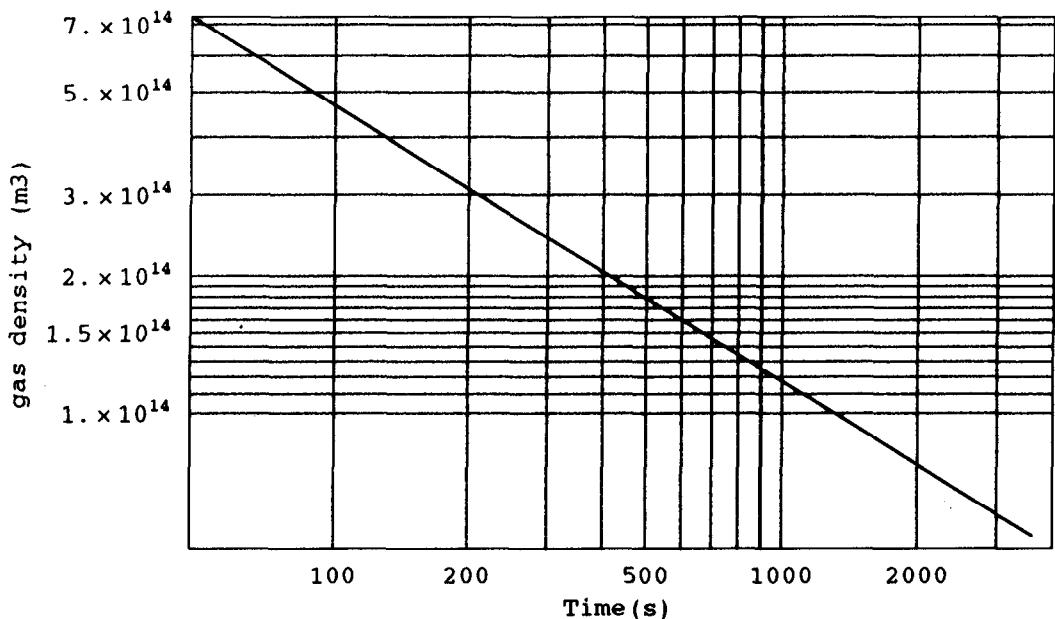
Secondary electron yield before and after photon  
scrubbing

## Electron Cloud Scrubbing in LHC

Linear power density: 0.5 W/m



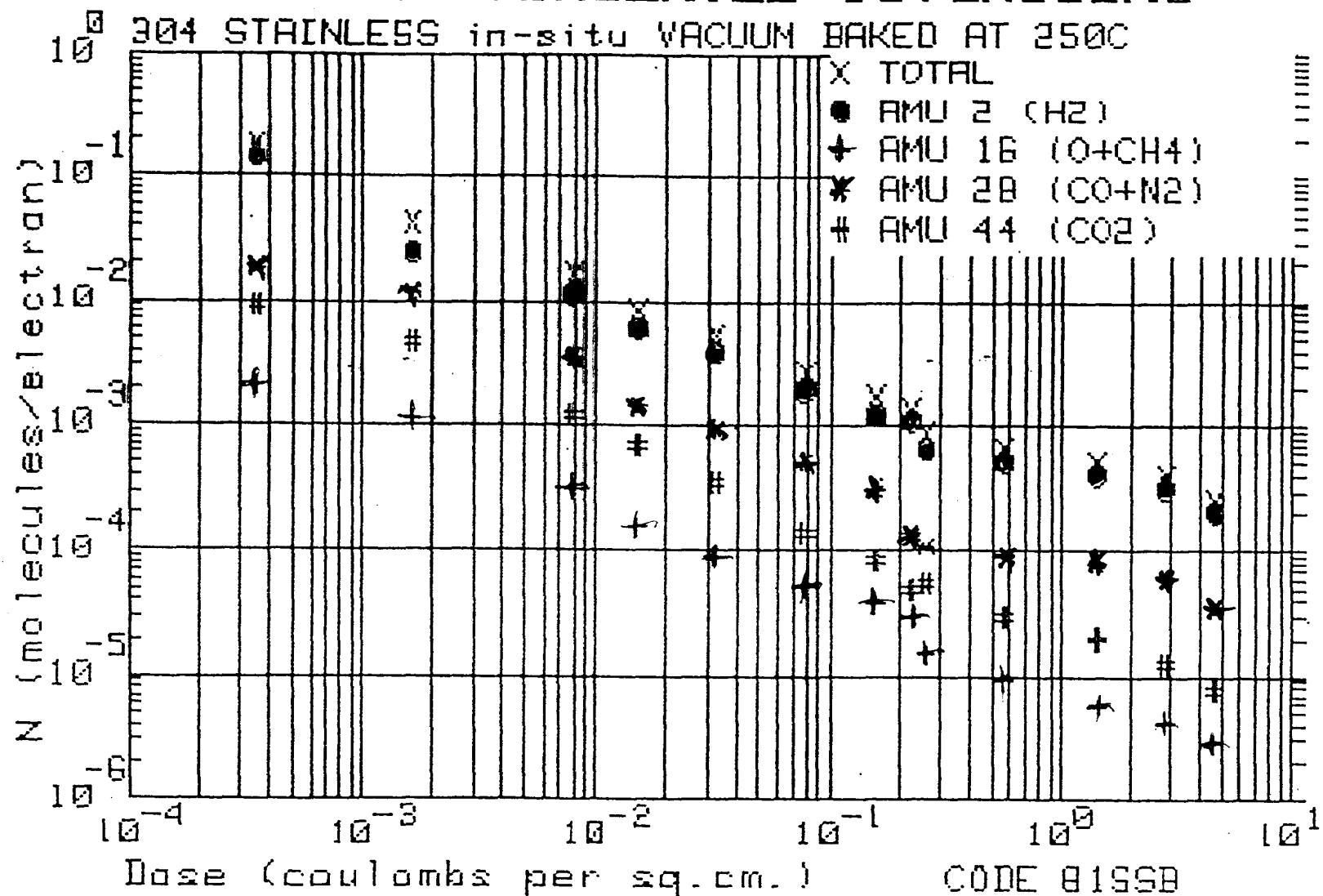
Electron stimulated desorption yield vrs. scrubbing time (s)



Electron cloud induced pressure rise vrs. time (s)

Lifetime limit density corresponds to  $10^{15}$  molecules/ $m^3$

# ELECTRON STIMULATED OUTGASSING



K. Kennedy  
LBL, 1986  
unpublished Note

Fig 10

## LHC Beam Screen Scrubbing Scenario

### I Photon scrubbing

First year operation at 7 TeV with  $\sim 1/5 I_{\text{nominal}}$  and below the cooling power limit.

compatible with dynamic vacuum pressure.

scrubbing time => 70 h

Subsequent years : with nominal beam current use gaps in bunch trains to avoid multipacting and to stay within the cooling power limit.

scrubbing time => reduced prop. with beam current

### II Electron scrubbing

Beam current limited by cooling power (0.5 W/m).

scrubbing dose  $\sim 10^{-3}$  C/mm<sup>2</sup> within < 1 hour

dynamic pressure rise remains below the lifetime limit and well below the magnet quench limit.

-> Electron scrubbing can be used to recondition a limited part of the machine in a shortest time. It may be done at injection energy but requires control of the beam.

## CONCLUSIONS/SUMMARY

LHC will depend on beam conditioning to operate with nominal beams :

dynamic pressure due to photon induced desorption  
(1/10 to 1/5 of nominal currents during first year)

e-Cloud effects (heat load) -> ~1/3 of nominal current during ~ 7Ah to reduce SEY < critical value of 1.3

Budget for beam screen cooling ~1W/m (two beams) is adequate for conditioning

Final heat load proportional to PEY -> suppression by dipole/quadrupole magnetic field : straight sections dominate

perp. photon incidence by saw tooth structure -> low reflectivity, PEY

Special surface coating/treatment to reduce conditioning time without photons in long straights/experimental vacuum chambers.

## **Future validations**

- 1) Photon scrubbing with a cryogenic system : ->  
COLDEX with EPA beams and in the SPS
  
- 2) SPS provides LHC type beams (but without  
synchrotron radiation) for multipacting studies (beam  
blow up, bunch trains, electron-conditioning, ...)
  
- 3) Special coatings/surface treatments to reduce  
conditioning time (dose, memory effect, ...)
  
- 4) Comparison between different machines which have  
shown/not shown e-Cloud effects
  
- 5) Fine tune, bench mark existing simulation codes  
beam pipe radius, pumping slots in beam screen